

**OLIFF & BERRIDGE, PLC**  
 ATTORNEYS AT LAW

**Application Data Sheet**

**Applicant Information**

Applicant Authority type::	Inventor
Primary Citizenship Country::	Japan
Status::	Full Capacity
Given Name::	Ryoji
Family Name::	HOSHI
City of Residence::	Fukushima
Country of Residence::	Japan

Applicant Authority Type::	Inventor
Primary Citizenship Country::	Japan
Status::	Full Capacity
Given Name::	Susumu
Family Name::	SONOKAWA
City of Residence::	Fukushima
Country of Residence::	Japan

**Correspondence Information**

Correspondence Customer Number::	25944
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**Application Information**

Application Type::	National Phase
Subject Matter::	Utility
CD-ROM or CD-R::	None
Title::	A SILICON WAFER FOR EPITAXIAL GROWTH, AN EPITAXIAL WAFER, AND A METHOD FOR PRODUCING IT
Attorney Docket Number::	122336
Total Drawing Sheets::	6
Small Entity::	No

**Representative Information**

James A. Oliff, Reg. No. 27,075

Kirk M. Hudson, Reg. No. 27,562

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<b>Domestic Priority Information</b>			
Application::	Continuity Type::	Parent Application::	Parent Filing Date::
This Application is a	National Stage of	PCT/JP03/08671	07/08/03
<b>Foreign Priority Information</b>			
Country::	Application Number::	Filing Date::	Priority Claimed::
Japan	2002-204703	07/12/02	Yes
<b>Assignee Information</b>			
Assignee Name::		Shin-Etsu Handotai Co., Ltd.	
Street of mailing address::		4-2, Marunouchi 1-chome, Chiyoda-ku	
City of mailing address::		Tokyo	
Country of mailing address::		Japan	